REFERENCE NUMERALS

Chemical vapor deposition system	100
Chamber body	102
Gas source	104
Walls	106
Bottom	108
Lid	110
Process volume	112
Pumping ring	114
Exhaust port	116
Showerhead	118
Interior side	120
Perimeter mounting ring	122
Dish-shaped center section	124
Mounting holes	126
Mounting screw	128
Mating hole	130
Perforated area	132
Mixing block	134
Blocker plate	136
Substrate support assembly	138
Underside	139
Substrate	140
Edge	141
Moveable shaft	142
Actuator	144
Bellows	146
Apparatuses	150
Slot	151
Apertures	152
Aperture	160
Pivot	200
Roller	202
Mounting flange	204
Lever	206
Arm	208
First end	210
Second end	212
First end	214
Second end	216
Pin	218
Biasing member	230
Torsion spring	232
Shaft	260

Substrate centering Apparatus	300
I-shaped pivot	302
Actuating arm	304
Mounting flange	306
Lever	308
Pivot arm	310
First end	312
Second end	314
Apertures	316
Substrate support assembly	318
Edge	320
Substrate	322
First end	324
Second end	326
Underside	328
Pin	330
Torsion spring	331
First end	332
Second end	334
Chamber bottom	336
Chamber	338
Lift pins	340
Lift plate	342
Apertures	344
First ends	346
Second ends	348
Apertures	350
Shaft	360
Aperture	362
Actuator	364
Bellows	366
Apparatus	400
Base	402
Lever	404
Roller arm	406
Slide	408
Ramp	410
First end	412
Second end	414
Underside	416
Support assembly	418
First end	420
Second end	422
Aperture	424
Edge	426

Substrate	428
First end	430
Second end	432
Roller	434
Bottom	436
Chamber	438
Sloped surface	450
Substantially flat surface	452
Spring	460
Assembly	500
Apparatus	502
Fixed pins	506
Support surface	508